

CPC COOPERATIVE PATENT CLASSIFICATION

B81B MICRO-STRUCTURAL DEVICES OR SYSTEMS, e.g. MICRO-MECHANICAL DEVICES (piezo-electric, electrostrictive or magnetostrictive elements [per se H01L 41/00](#))

NOTES

1. This subclass does not cover:
 - purely electrical or electronic devices per se which are covered by section [H](#), e.g. subclass [H01L](#);
 - purely optical devices per se which are covered by subclasses [G02B](#) or [G02F](#);
 - essentially two-dimensional structures, e.g. layered products which are covered by subclass [B32B](#);
 - chemical or biological structures per se which are covered by section [C](#);
 - structures in atomic scale produced by manipulation of single atoms or molecules, which are covered by group [B82B 1/00](#).
2. Devices or systems classified in this subclass are also classified in appropriate subclasses providing for their structural or functional features, if such features are of interest.
3. Attention is drawn to the following places:
 - [A61K 9/50](#) Microcapsules for medicinal preparations
 - [B25J 7/00](#) Micromanipulators
 - [G02B 21/32](#) Micromanipulators combined with microscopes
 - [G11B 5/127](#) Magnetic heads
 - [H01P 3/08](#) Waveguide microstrips.
4. In this subclass, local "residual" subgroups, e.g. [B81B 7/0077](#), are used with the following purpose:

When classifying a document which does not fit in any of a set of subgroups with the same dot-level, the document should be classified in the residual group, if present, and not in the group at the hierarchical level one dot above.

In the example, the document shall be classified in [B81B 7/0077](#) and not in [B81B 7/0032](#) as [B81B 7/0077](#) is "residual" to [B81B 7/0035-B81B 7/0074](#)

1/00	Devices without movable or flexible elements, e.g. micro-capillary devices	3/0024	. . {Transducers for transforming thermal into mechanical energy or <u>vice versa</u> , e.g. thermal or bimorph actuators (electric motors using thermal effects H02N 10/00)}
1/002	. {Holes characterised by their shape, in either longitudinal or sectional plane}		
1/004	. . {Through-holes, i.e. extending from one face to the other face of the wafer}	3/0027	. . {Structures for transforming mechanical energy, e.g. potential energy of a spring into translation, sound into translation}
1/006	. {Microdevices formed as a single homogeneous piece, i.e. wherein the mechanical function is obtained by the use of the device, e.g. cutters}	3/0029	. . {Transducers for transforming light into mechanical energy or viceversa}
1/008	. . {Microtips}	3/0032	. . {Structures for transforming energy not provided for in groups B81B 3/0021 - B81B 3/0029 }
3/00	Devices comprising flexible or deformable elements, e.g. comprising elastic tongues or membranes (B81B 5/00 takes precedence)	3/0035	. {Constitution or structural means for controlling the movement of the flexible or deformable elements}
3/0002	. {Arrangements for avoiding sticking of the flexible or moving parts}	3/0037	. . {For increasing stroke, i.e. achieve large displacement of actuated parts}
3/0005	. . {Anti-stiction coatings}	3/004	. . {Angular deflection}
3/0008	. . {Structures for avoiding electrostatic attraction, e.g. avoiding charge accumulation}	3/0043	. . . {Increasing angular deflection}
3/001	. . {Structures having a reduced contact area, e.g. with bumps or with a textured surface}	3/0045	. . . {Improve properties related to angular swinging, e.g. control resonance frequency}
3/0013	. . {Structures dimensioned for mechanical prevention of stiction, e.g. spring with increased stiffness}	3/0048	. . . {Constitution or structural means for controlling angular deflection not provided for in groups B81B 3/0043 - B81B 3/0045 }
3/0016	. . {Arrangements for avoiding sticking of the flexible or moving parts not provided for in groups B81B 3/0005 - B81B 3/0013 }	3/0051	. . {For defining the movement, i.e. structures that guide or limit the movement of an element (mechanical arrangements for preventing or damping vibration or shock H01H 3/60)}
3/0018	. {Structures acting upon the moving or flexible element for transforming energy into mechanical movement or <u>vice versa</u> , i.e. actuators, sensors, generators}	3/0054	. . {For holding or placing an element in a given position}
3/0021	. . {Transducers for transforming electrical into mechanical energy or <u>vice versa</u> (dynamo-electric machines H02K 99/00 ; electrostatic machines H02N 1/00 ; piezo-electric devices H01L 41/00)}	3/0056	. . {Adjusting the distance between two elements, at least one of them being movable, e.g. air-gap tuning}
		3/0059	. . {Constitution or structural means for controlling the movement not provided for in groups B81B 3/0037 - B81B 3/0056 }

- 3/0062 . {Devices moving in two or more dimensions, i.e. having special features which allow movement in more than one dimension}
- 3/0064 . {Constitution or structural means for improving or controlling the physical properties of a device}
- 3/0067 . . {Mechanical properties}
- 3/007 . . . {For controlling stiffness, e.g. ribs}
- 3/0072 . . . {For controlling internal stress or strain in moving or flexible elements, e.g. stress compensating layers}
- 3/0075 . . . {For improving wear resistance}
- 3/0078 . . . {Constitution or structural means for improving mechanical properties not provided for in [B81B 3/007](#) - [B81B 3/0075](#)}
- 3/0081 . . {Thermal properties}
- 3/0083 . . {Optical properties}
- 3/0086 . . {Electrical characteristics, e.g. reducing driving voltage, improving resistance to peak voltage}
- 3/0089 . . {Chemical or biological characteristics, e.g. layer which makes a surface chemically active}
- 3/0091 . . {Magnetic properties, e.g. guiding magnetic flux}
- 3/0094 . . {Constitution or structural means for improving or controlling physical properties not provided for in [B81B 3/0067](#) - [B81B 3/0091](#)}
- 3/0097 . {Devices comprising flexible or deformable elements not provided for in groups [B81B 3/0002](#) - [B81B 3/0094](#)}
- 5/00** **Devices comprising elements which are movable in relation to each other, e.g. comprising slidable or rotatable elements**
- 7/00** **Micro-structural systems; {Auxiliary parts of micro-structural devices or systems}**
- 7/0003 . {MEMS mechanisms for assembling automatically hinged components, self-assembly devices (self-assembly processes [B81C 1/00007](#))}
- 7/0006 . {Interconnects}
- 7/0009 . {Structural features, others than packages, for protecting a device against environmental influences ([B81C 1/00777](#) takes precedence)}
- 7/0012 . . {Protection against reverse engineering, unauthorised use, use in unintended manner, wrong insertion or pin assignment}
- 7/0016 . . {Protection against shocks or vibrations, e.g. vibration damping}
- 7/0019 . . {Protection against thermal alteration or destruction ([B81B 7/0083](#) takes precedence)}
- 7/0022 . . {Protection against electrostatic discharge (electrostatic discharge protection for electronic semiconductor circuits [H01L 27/0248](#); circuit arrangements for protecting electronic switching circuits used for pulse technique against overcurrent or overvoltage [H03K 17/08](#))}
- 7/0025 . . {Protection against chemical alteration}
- 7/0029 . . {Protection against environmental influences not provided for in groups [B81B 7/0012](#) - [B81B 7/0025](#)}
- 7/0032 . {Packages or encapsulation (processes for packaging MEMS [B81C 1/00261](#); packaging of smart-MEMS [B81C 1/0023](#))}
- 7/0035 . . {for maintaining a controlled atmosphere inside of the chamber containing the MEMS}
- 7/0038 . . . {using materials for controlling the level of pressure, contaminants or moisture inside of the package, e.g. getters}
- 7/0041 . . . {maintaining a controlled atmosphere with techniques not provided for in [B81B 7/0038](#)}
- 7/0045 . . {for reducing stress inside of the package structure}
- 7/0048 . . . {between the MEMS die and the substrate}
- 7/0051 . . . {between the package lid and the substrate}
- 7/0054 . . . {between other parts not provided for in [B81B 7/0048](#) - [B81B 7/0051](#)}
- 7/0058 . . {for protecting against damages due to external chemical or mechanical influences, e.g. shocks or vibrations}
- 7/0061 . . {suitable for fluid transfer from the MEMS out of the package or *vice versa*, e.g. transfer of liquid, gas, sound}
- 7/0064 . . {for protecting against electromagnetic or electrostatic interferences}
- 7/0067 . . {for controlling the passage of optical signals through the package}
- 7/007 . . {Interconnections between the MEMS and external electrical signals}
- 7/0074 . . {3D packaging, i.e. encapsulation containing one or several MEMS devices arranged in planes non-parallel to the mounting board}
- 7/0077 . . {Other packages not provided for in groups [B81B 7/0035](#) - [B81B 7/0074](#)}
- 7/008 . {MEMS characterised by an electronic circuit specially adapted for controlling or driving the same ([B81B 7/0087](#) takes precedence; arrangements for starting, regulating, braking, or otherwise controlling an actuator [H02N](#); control arrangements or circuits for visual indicators [G09G 3/00](#))}
- NOTES**
- 1. This group covers: only MEMS with an electronic circuit which is not specific to a particular application.
- 2. This group does not cover: electronic circuits per se, e.g. for controlling or driving application specific MEMS
- 7/0083 . {Temperature control}
- 7/0087 . . {On-device systems and sensors for controlling, regulating or monitoring}
- 7/009 . . {Maintaining a constant temperature by heating or cooling}
- 7/0093 . . . {by cooling}
- 7/0096 . . . {by heating}
- 7/02 . containing distinct electrical or optical devices of particular relevance for their function, e.g. micro-electro-mechanical systems [MEMS] ([B81B 7/04](#) takes precedence)
- 7/04 . Networks or arrays of similar micro-structural devices
- 2201/00** **Specific applications of micro-electromechanical systems**
- 2201/01 . Switches
- 2201/012 . . characterised by the shape
- 2201/014 . . . having a cantilever fixed on one side connected to one or more dimples
- 2201/016 . . . having a bridge fixed on two ends and connected to one or more dimples

2201/018	. . . Switches not provided for in B81B 2201/014 - B81B 2201/016	2203/0163	. . . Spring holders
2201/02	. Sensors	2203/0172	. . . Flexible holders not provided for in B81B 2203/0154 - B81B 2203/0163
2201/0207	. . Bolometers	2203/0181	. . See-saws
2201/0214	. . Biosensors; Chemical sensors	2203/019	. . characterized by their profile
2201/0221	. . Variable capacitors	2203/03	. Static structures
2201/0228	. . Inertial sensors	2203/0307	. . Anchors
2201/0235	. . . Accelerometers	2203/0315	. . Cavities
2201/0242	. . . Gyroscopes	2203/0323	. . Grooves
2201/025	. . . Inertial sensors not provided for in B81B 2201/0235 - B81B 2201/0242	2203/033	. . . Trenches
2201/0257	. . Microphones or microspeakers	2203/0338	. . . Channels
2201/0264	. . Pressure sensors	2203/0346	. . . Grooves not provided for in B81B 2203/033 - B81B 2203/0338
2201/0271	. . Resonators; ultrasonic resonators	2203/0353	. . Holes
2201/0278	. . Temperature sensors	2203/0361	. . Tips, pillars
2201/0285	. . Vibration sensors	2203/0369	. . characterized by their profile
2201/0292	. . Sensors not provided for in B81B 2201/0207 - B81B 2201/0285	2203/0376	. . . rounded profile
2201/03	. Micro-engines and actuators	2203/0384	. . . sloped profile
2201/031	. . Thermal actuators	2203/0392	. . . profiles not provided for in B81B 2203/0376 - B81B 2203/0384
2201/032	. . Bimorph and unimorph actuators, e.g. piezo and thermo	2203/04	. Electrodes
2201/033	. . Comb drives	2203/05	. Type of movement
2201/034	. . Electrical rotating micro-machines	2203/051	. . Translation according to an axis parallel to the substrate
2201/035	. . Micro-gears	2203/053	. . Translation according to an axis perpendicular to the substrate
2201/036	. . Micro-pumps	2203/055	. . Translation in a plane parallel to the substrate, i.e. enabling movement along any direction in the plane
2201/037	. . Micro-transmissions	2203/056	. . Rotation in a plane parallel to the substrate
2201/038	. . Micro-engines and actuators not provided for in B81B 2201/031 - B81B 2201/037	2203/058	. . Rotation out of a plane parallel to the substrate
2201/04	. Optical MEMS	2203/06	. Devices comprising elements which are movable in relation to each other, e.g. slidable or rotatable
2201/042	. . Micro-mirrors, not used as optical switches		
2201/045	. . Optical switches	2207/00	Micro-structural systems or auxiliary parts thereof
2201/047	. . Optical MEMS not provided for in B81B 2201/042 - B81B 2201/045	2207/01	. comprising a micromechanical device connected to control or processing electronics, i.e. Smart-MEMS
2201/05	. Micro-fluidics	2207/012	. . the micromechanical device and the control or processing electronics being separate parts in the same package
2201/051	. . Micro-mixers, micro-reactors	2207/015	. . the micromechanical device and the control or processing electronics being integrated on the same substrate
2201/052	. . Ink-jet print cartridges	2207/017	. . Smart-MEMS not provided for in B81B 2207/012 - B81B 2207/015
2201/054	. . Micro-valves	2207/03	. Electronic circuits for micro-mechanical devices which are not application specific, e.g. for controlling, power supplying, testing, protecting
2201/055	. . Micro-needles	2207/05	. Arrays
2201/057	. . Micropipets, dropformers	2207/053	. . of movable structures
2201/058	. . Micro-fluidics not provided for in B81B 2201/051 - B81B 2201/054	2207/056	. . of static structures
2201/06	. Bio-MEMS	2207/07	. Interconnects
2201/07	. Data storage devices, static or dynamic memories	2207/09	. Packages
2201/10	. Micro-filters, e.g. for gas or fluids	2207/091	. . Arrangements for connecting external electrical signals to mechanical structures inside the package
2201/11	. Read heads, write heads or micro-positioners for hard- or optical disks	2207/092	. . . Buried interconnects in the substrate or in the lid
2201/12	. STM or AFM micro-tips	2207/093	. . . Conductive package seal
2201/13	. Mechanical connectors, i.e. not functioning as an electrical connector	2207/094	. . . Feed-through, via
2203/00	Basic micro-electromechanical structures	2207/095 through the lid
2203/01	. Suspended structures, i.e. structures allowing a movement	2207/096 through the substrate
2203/0109	. . Bridges		
2203/0118	. . Cantilevers		
2203/0127	. . Diaphragms, i.e. structures separating two media that can control the passage from one medium to another; Membranes, i.e. diaphragms with filtering function		
2203/0136	. . Comb structures		
2203/0145	. . Flexible holders		
2203/0154	. . . Torsion bars		

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- 2207/097 . . . Interconnects arranged on the substrate or the lid, and covered by the package seal
- 2207/098 . . . Arrangements not provided for in groups [B81B 2207/092](#) - [B81B 2207/097](#)
- 2207/11 . . Structural features, others than packages, for protecting a device against environmental influences
- 2207/115 . . Protective layers applied directly to the device before packaging
- 2207/99 . . Micro-structural systems or auxiliary parts thereof not provided for in [B81B 2207/01](#) - [B81B 2207/115](#)